Strip Ion Source Plasma Generating Power Source

Product Code: Strip Ion Source Plasma Generating Power Source
Weight: 0.00kg
Dimensions: 0.00cm x 0.00cm x 0.00cm

Short Description

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The anode layer ion source is applied to ion cleaning of large-area coating, auxiliary deposition, tool coating, plastic substrate modification and the like.

The main circuit topology adopts PFC + PF full-bridge architecture combined with ARM + DSP ARM + DSP ARM + DSP digital control technology.

At the same time, the V-ARCI-ARC can quickly cut off the output and start the built-in patented technology to eliminate the residual arc energy, avoid the substrate discharge and arc striking, ensure the high-precision film layer, and improve the yield, surface finish and film binding force of the plated parts.

Constant current/constant voltage optional

Configuration panel operation and display: remote PLC control

Communication interface: Analog; Modbus; PROFIBUS; EtherCAT